



RESPONSE UNDER 37 CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 3161

00862.022168

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Seiji TAKEUCHI et al.) : Examiner: A. Kosowski
Application No.: 09/819,670) : Group Art Unit: 2125
Filed: March 29, 2001) : Confirmation No.: 3161
For: STOCKER, EXPOSURE APPARATUS,) July 14, 2004
DEVICE MANUFACTURING METHOD,)
SEMICONDUCTOR MANUFACTURING)
FACTORY, AND EXPOSURE APPARATUS :
MAINTENANCE METHOD)

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JUL 16 2004

Technology Center 2100

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT AFTER FINAL REJECTION

Sir:

In response to the final Official Action dated April 14, 2004, please amend the above-identified application as follows, pursuant to 37 C.F.R. § 1.116: